Tuning the Voltage Controlled Magnetic Anisotropy in CoFeB/MgO Magnetic Tunnel Junctions



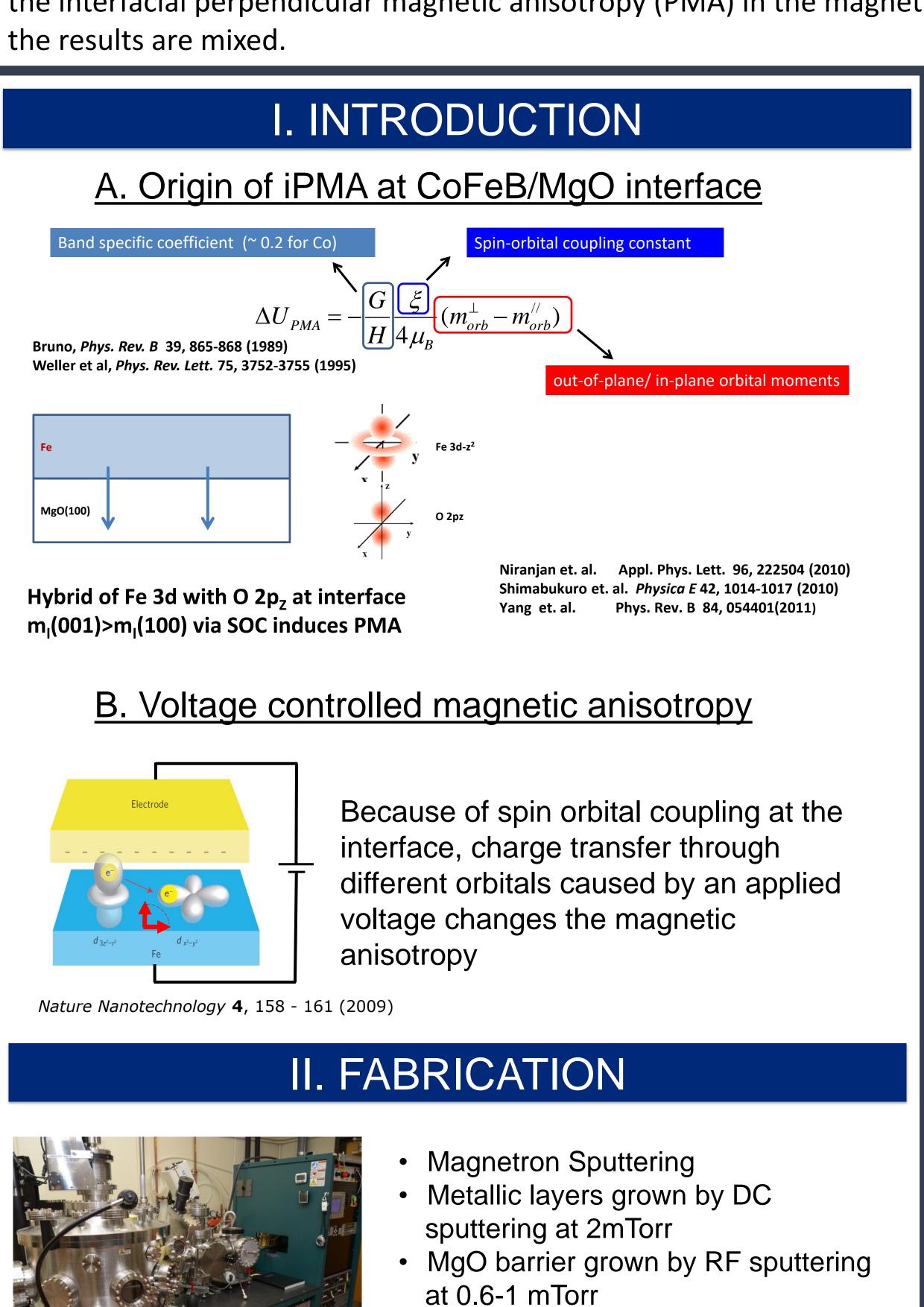
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BACKGROUND

Magnetic tunnel junctions (MTJ) are promising candidates for next generation nonvolatile memory and logic applications. In MTJs with perpendicular anisotropy (pMTJ), the voltage controlled magnetic anisotropy (VCMA) effect has been demonstrated and has drawn a lot of attention for its potential application of ultra-low energy switching. The VCMA coefficient, which describes the effectiveness of electric field in modulating the interfacial perpendicular magnetic anisotropy (PMA) in the magnetic layer, still sits below 300 fJ/Vm and leaves much to be desired for further application. Much effort has been focused on enhancing VCMA, and the results are mixed.

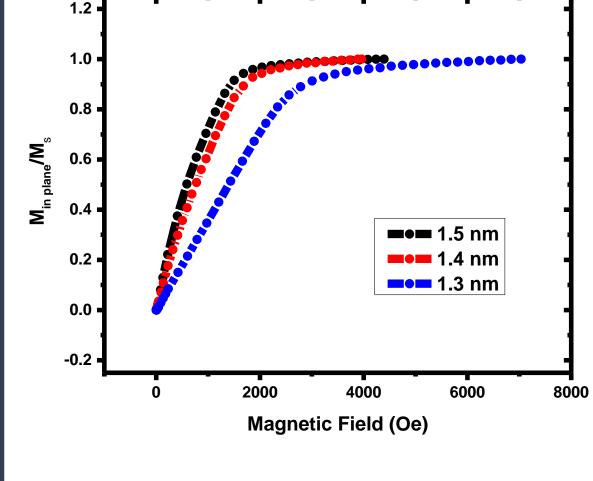


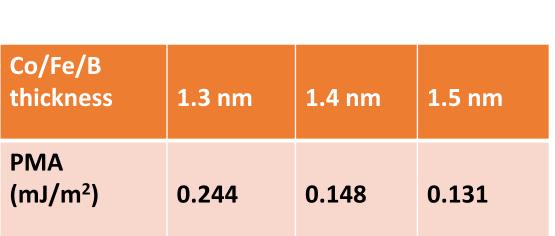
Standard photolithography

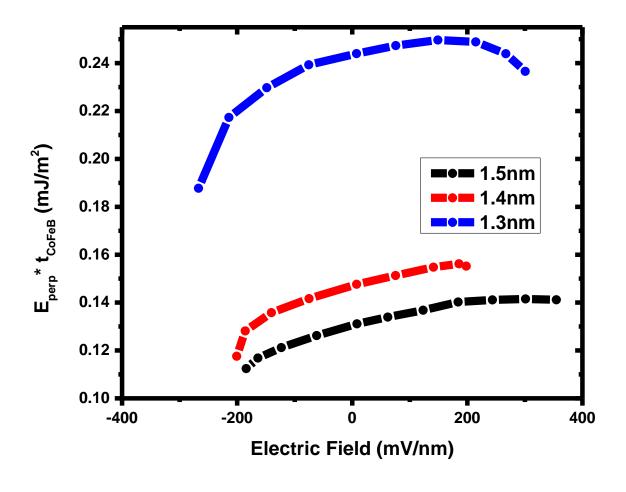
Measuring resistance within a range of magnetic field strength gives the in plane component of the saturation magnetization. $\frac{M_{in\,plane}}{M_s} = \frac{R_{90} - R(\theta)}{R(\theta)} \frac{R_p}{R_{90} - R_p}$ $\frac{M_{in\,plane}}{M_s} = \frac{R_{90} - R(\theta)}{R(\theta)} \frac{R_p}{R_{90} - R_p}$ $W = \int_{0.000}^{M} H dM \frac{erg}{cm^3}$

IV. RESULTS AND DISCUSSION

A. Different CoFeB Thickness







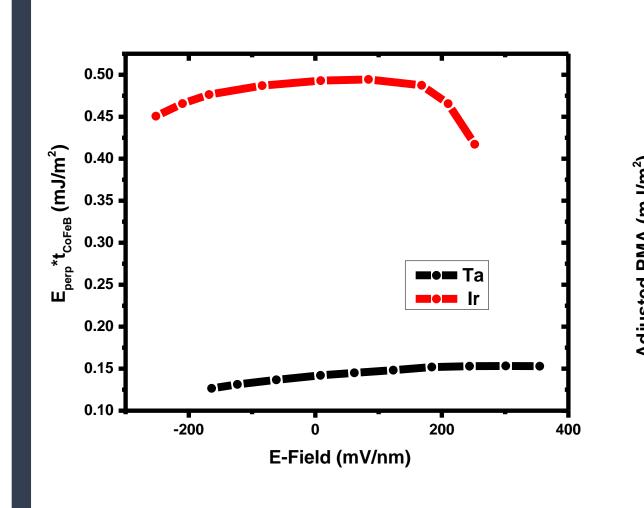
Co/Fe/B thickness	1.3 nm	1.4 nm
VCMA Coefficient (fJ/Vm)	51.4	71.8

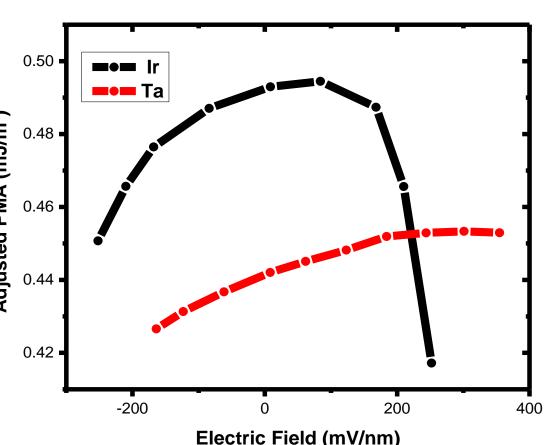
1.5 nm

59.8

IV. RESULTS AND DISCUSSION

B. Different Underlayer (Ta and Ir)





Different PMA-electric field behavior for different underlayer!

V. CONCLUSION

- ★ Variation in CoFeB thickness can modulate VCMA coefficient at CoFeB/MgO interface
- ★ Large enhancement of PMA using iridium as underlayer with dramatically different PMA-Electric Field dependence

VI. NEXT STEPS

- ★ Insertion of heavy metals between CoFeB and MgO for their strong spin orbital coupling
- ★ Exploration of the nonlinear relationship between PMA and electric field under different annealing conditions

ACKNOWLEDGMENTS

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